

Application Serial Number: 09/577,932
Group Art Unit: 2815

Page 2

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a plurality of metal posts formed on the electrode pads of the redistribution layer, the metal posts being configured to be provided with external connection electrodes; and at least one mark member which serves as an alignment mark located in a predetermined positional relationship with the metal posts,
wherein the mark member is made of the same material as the metal posts.

2. The semiconductor device as claimed in claim 1, wherein the alignment mark has an outer configuration other than a circle.

3. The semiconductor device as claimed in claim 1, wherein a width of the alignment mark measured along a plane parallel to a surface of the redistribution layer is greater than a height of the metal posts.

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4. A semiconductor device comprising:
a semiconductor element having a plurality of electrodes;
a redistribution layer which connects the electrodes of the semiconductor device to electrode pads located in predetermined positions of the redistribution layer; and at least one mark member which serves as an alignment mark located in a predetermined positional relationship with the electrode pads, wherein the mark member is made of the same material with the electrode pads.

Application Serial Number: 09/577,932
Group Art Unit: 2815

Page 3

5. The semiconductor device as claimed in claim 4, wherein the alignment mark has an outer configuration other than a circle.

Mark 3
13. (Three-times Amended) An apparatus for fixing a semiconductor wafer by suction, comprising:

a vacuum chuck table having a porous plate overlaying a plurality of concentric suction grooves;

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a plurality of suction passages being connected to the plurality of concentric suction grooves, the plurality of concentric suction grooves being divided into a plurality of groups so that each of the plurality of suction passages is connected to one of a corresponding suction groove belonging to one of the plurality of groups; and

means for sequentially introducing a suctioning force into the suction passages at different timing.